

AMENDMENTS TO THE CLAIMS:

This listing of claims will replace all prior versions, and listings, of claims in the application:

LISTING OF CLAIMS:

1. (Previously Presented) A solid electrolyte having the formula of $\text{Li}_x\text{Si}_y\text{M}_z\text{O}_v\text{N}_w$ where $0.3 \leq x \leq 0.46$, $0.05 \leq y \leq 0.15$, $0.016 \leq z < 0.05$, $0.42 \leq v < 0.5$, $0 \leq w \leq 0.029$, and M is at least one selected from the group consisting of Nb, Ta, and W.
2. (Previously Presented) A method of manufacturing the solid electrolyte of claim 1 using targets consisting essentially of Li_2O , SiO_2 , and at least one selected from the group consisting of Nb_2O_5 , Ta_2O_5 , and WO_3 , and optionally nitrogen gas, as source materials by one of simultaneous sputtering, electron beam deposition, ion beam deposition, and chemical vapor deposition.
3. (Original) The method of claim 2, wherein a reactant gas containing nitrogen is used.
4. (Original) A lithium battery employing the solid electrolyte of claim 1.
5. (Original) A thin-film battery employing the solid electrolyte of claim 1.

6. (Previously Presented) A solid electrolyte having the formula of $\text{Li}_x\text{Si}_y\text{M}_z\text{O}_v\text{N}_w$ where $0.3 \leq x \leq 0.46$, $0.05 \leq y \leq 0.15$, $0.016 \leq z < 0.05$, $0.42 \leq v < 0.5$, $0 \leq w \leq 0.029$, and M is Nb.

7. (Previously Presented) A method of manufacturing the solid electrolyte of claim 6 using targets consisting essentially of Li_2O , SiO_2 , and Nb_2O_5 , and optionally nitrogen gas, as source materials by one of simultaneous sputtering, electron beam deposition, ion beam deposition, and chemical vapor deposition.

8. (Currently Amended) The method of [[claim 6]] claim 7 wherein a reactant gas containing nitrogen is used.

9. (Previously Presented) A lithium battery employing the solid electrolyte of claim 6.

10. (Previously Presented) A thin-film battery employing the solid electrolyte of claim 6.